

# Simulation of Pixel Voltage Error for a-Si TFT LCD Regarding the Change in LC Pixel Capacitance

Yongfu Zhu, Muju Li, Jianfeng Yuan, Chuanzhen Liu, Bailiang Yang, and Dezhen Shen

**Abstract**—LC pixel capacitance  $C_{lc}$ , which changes with the director of liquid crystal molecules as a function of external applied voltage, has a most important impact on the pixel voltage error  $\Delta V_p$  and therefore on the electro-optics (E-O) characteristics of LC pixel for a-Si TFT LCD. In this paper, the pixel voltage error has been simulated for 10.4" VGA (640 × 480) and SVGA (800 × 600) a-Si TFT LCD, and in this simulation, we especially took into account the change in LC dielectric constant. We found that  $\Delta V_p$  changes with the data voltage  $V_p$ . In addition, E-O characteristics of LC pixel for a-Si TFT LCD has been investigated. The result shows that the effect of  $\Delta V_p$  on E-O characteristics is significant when  $V_p$  ranges from the threshold voltage to the saturation voltage.

**Index Terms**—Electro-optical characteristics, liquid crystal capacitance, liquid crystal displays, thin-film transistor, voltage error.

## I. INTRODUCTION

**A**MORPHOUS-SILICON thin-film transistors (a-Si TFT) are of considerable interest for applications involving large-area active matrix-addressed liquid crystal displays (AM-LCD). Though a great progress has been made in a-Si TFT AM-LCD, the study of some subjects remains active to improve the performance.

When a-Si TFT is turned off at the end of a charging period, there is a voltage error  $\Delta V_p$  induced on the pixel electrode. The voltage error  $\Delta V_p$  is a serious problem to large area and high-resolution a-Si TFT LCD because it results in the electro-optics (E-O) characteristics error, which leads to display deterioration such as flickers [1], shadings [2], and gray scale error [3].

Papers have been presented to discuss  $\Delta V_p$  to solve this problem [4]–[6]. Some suggest that  $\Delta V_p$  is induced by the crossover capacitance  $C_{gd}$  due to overlaps between the gate and the drain electrode of TFT, and that  $\Delta V_p$  is independent on the data voltage  $V_p$ . However, replacing the LC pixel capacitance by a constant capacitor, the experiment [7] showed that  $\Delta V_p$  is linear with  $V_p$ . This result can be explained if the channel capacitance  $C_g$  is included [8]. Theoretic work [9] also proved that  $\Delta V_p$  depends evidently on the channel capacitance  $C_g$  between the channel at the source side and gate electrode.

Though much research work has been devoted in this area, there has been no a clear interpretation for voltage error  $\Delta V_p$ . As we know, the LC director changes with the external applied

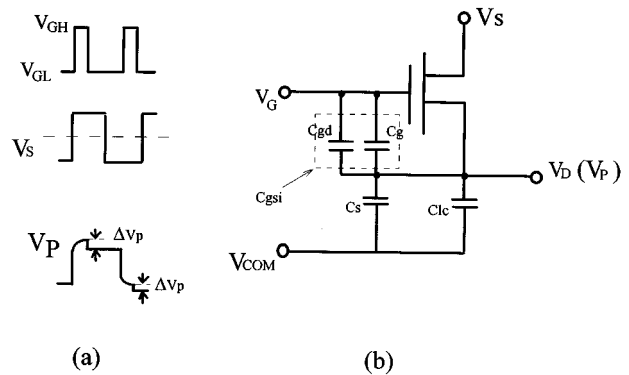


Fig. 1. Schematic diagram of the driving waveform and the equivalent circuit of LC pixel for a-Si TFT LCD.

voltage, and this produce a change in LC capacitance. However, this factor was neglected in previous work. In this paper, by taking into account this change, the voltage error  $\Delta V_p$  and E-O characteristics of LC pixel have been simulated for 10.4" VGA and SVGA a-Si TFT AM-LCD.

## II. THE CAPACITANCE IN CIRCUITS FOR LC PIXEL OF A-SI TFT LCD

The schematic diagram of the driving waveform and the equivalent circuit for LC pixel of a-Si TFT LCD is shown in Fig. 1. When the gate pulse changes from  $V_{GH}$  to  $V_{GL}$ , there is a decrease  $\Delta V_p$  in the drain pixel voltage  $V_p$  referring the ON state of a-Si TFT. The capacitance in this circuit includes the crossover capacitance  $C_{gd}$ , the storage capacitance  $C_s$ , the channel capacitance  $C_g$ , and the LC capacitance  $C_{lc}$ . Here, we define  $C_{gsi}$  as the combination of  $C_{gd}$  and  $C_g$ .  $C_{gsi}$  is the total of  $C_{gd}$  and a half of  $C_g$  when a-Si TFT is on, thus  $C_{gsi}$  referring ON and OFF state of a-Si TFT can be expressed as [8]

$$C_{gs\text{on}} = C_{gd} + \frac{C_g}{2} \quad \text{ON STATE} \quad (1)$$

$$C_{gs\text{off}} = C_{gd} \quad \text{OFF STATE} \quad (2)$$

respectively.

The storage capacitor plays the role to eliminate the pixel voltage error, and its area is one of the main factors determining the aperture ratio of a-Si TFT array.

The director of liquid crystal changes with external applied voltage, and this result in a change in the LC dielectric constant and therefore in the LC capacitance. According to Oseen–Frank continuum theory, Ling *et al.* simulated the configuration of

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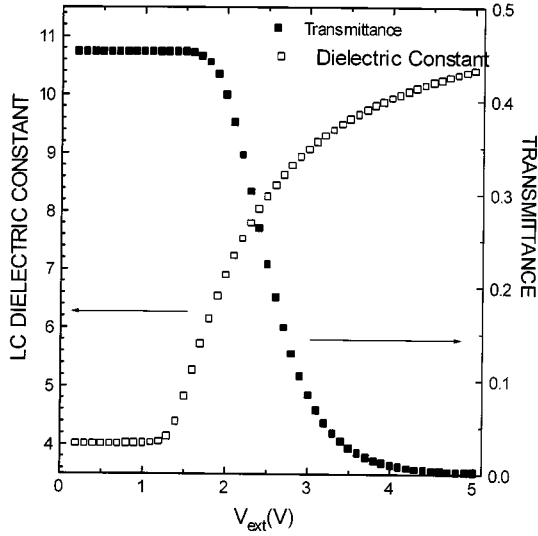


Fig. 2. LC dielectric constant and transmittance as a function of various external applied voltage.

liquid crystal director and E-O characteristics under different external applied voltage for passive matrix LCD [10]. To obtain the effective LC dielectric constant under various voltages  $V_p$ , the whole cell is divided into 100 layers. Then based on the work of Ling *et al.*, we get the LC dielectric constant of every single layer. Finally, the effective dielectric constant value of LC pixel under different external applied voltages can be obtained. Together with E-O characteristics, the effect of the external applied voltage  $V_{ext}$  on the LC dielectric constant is shown in Fig. 2.

### III. MODEL

As described above, the alternation between ON and OFF state of a-Si TFT leads to a voltage error  $\Delta V_p$  for LC pixel, and it then results in a slight change in LC dielectric constant. According to the law of conservation of electric charge, we have

$$(V_p - V_{com})(C_{lc\ on} + C_s) + (V_p - V_{GH})C_{gs\ on} = (V'_p - V_{com})(C_{lc\ off} + C_s) + (V'_p - V_{GL})C_{gs\ off} \quad (3)$$

$$V'_p = V_p - \Delta V_p \quad (4)$$

where

$C_{lc\ on}$ ,  $C_{lc\ off}$  LC pixel capacitance referring ON and OFF state of a-Si TFT, respectively;  
 $V_{COM}$  voltage of common electrode;  
 $V_p$  data voltage, i.e., the LC pixel voltage referring ON state of TFT;  
 $V'_p$  LC pixel voltage referring OFF state of TFT.  
 So,  $\Delta V_p$  can be taken from (1)–(4):

$$\Delta V_p = \frac{(V_{com} - V_p)(C_{lc\ on} - C_{lc\ off}) + \Delta V_g C_{gd} + (V_{GH} - V_p)C_g / 2}{C_{gd} + C_{lc\ off} + C_s} \quad (5)$$

TABLE I  
PARAMETERS OF a-Si TFT LCD USED IN THE SIMULATION

Parameter	Value
Channel area ( $\mu\text{m}^2$ )	1000
Dielectric constant of a-SiN <sub>x</sub>	6.9
Thickness of a-SiN <sub>x</sub> layer(nm)	400
LC cell gap( $\mu\text{m}$ )	5
On state gate voltage(V)	15
Off state gate voltage(V)	-5
Common electrode voltage(V)	5
Area of crossover capacitance ( $\mu\text{m}^2$ )	300

where

$$C_{lc\ off} = \epsilon_o \epsilon_{off} s_{lc} / d_{lc}$$

$$C_{lc\ on} = \epsilon_o \epsilon_{on} s_{lc} / d_{lc}$$

$$C_g = \epsilon_o \epsilon_i s_{TFT} / d_i$$

$$C_{gd} = \epsilon_o \epsilon_i s_{gd} / d_i$$

$$C_s = \epsilon_o \epsilon_i s_s / d_i$$

$$\Delta V_G = V_{GH} - V_{GL}$$

where

$\epsilon_o$  and  $\epsilon_i$  vacuum dielectric constant and the dielectric constant of a-SiN<sub>x</sub>;  
 $s_{lc}$  area of the LC pixel;  
 $s_s$  area of the storage capacitance;  
 $s_{TFT}$  and  $s_{gd}$  the area of TFT channel and the crossover capacitance, respectively;  
 $d_{lc}$  and  $d_i$  the LC gap and the thickness of insulator layer, respectively,  
 $\epsilon_{on}$  and  $\epsilon_{off}$  LC dielectric constant referring ON and OFF state of TFT, respectively;  
 $V_{GH}$  and  $V_{GL}$  ON-state and OFF-state gate voltage of TFT, respectively.

### IV. RESULTS AND DISCUSSION

#### A. Voltage Error for the Pixel Electrode

The parameters of a-Si TFT LCD array used in the calculation are summarized in Table I. Applying the LC dielectric constant as a function of the external applied voltage to formulation (5), we obtained the dependence of  $\Delta V_p$  on data voltage  $V_p$  for 10.4" VGA and SVGA a-Si TFT AM-LCD in Fig. 3. When  $V_p$  is below the threshold voltage, for a-Si TFT LCD without  $C_s$ -design, there is a slight increase in  $\Delta V_p$ , and in contrast, in the case that  $C_{st}$  is adopted, as means a reduction in the aperture ratio, there is almost no change in  $\Delta V_p$ . When  $V_p$  ranges from the threshold voltage to the saturation voltage,  $\Delta V_p$  decreases abruptly with  $V_p$ . If  $V_p$  is over the saturation voltage,  $\Delta V_p$  increases very slowly.

For 10.4" TFT LCD with the same resolution, the higher the aperture ratio is, the higher  $\Delta V_p$  is. On the other hand, for 10.4" a-Si TFT LCD with the same aperture ratio,  $\Delta V_p$  for SVGA is higher than that for VGA, as is clearly shown from the comparison of Fig. 4(a) and (b).

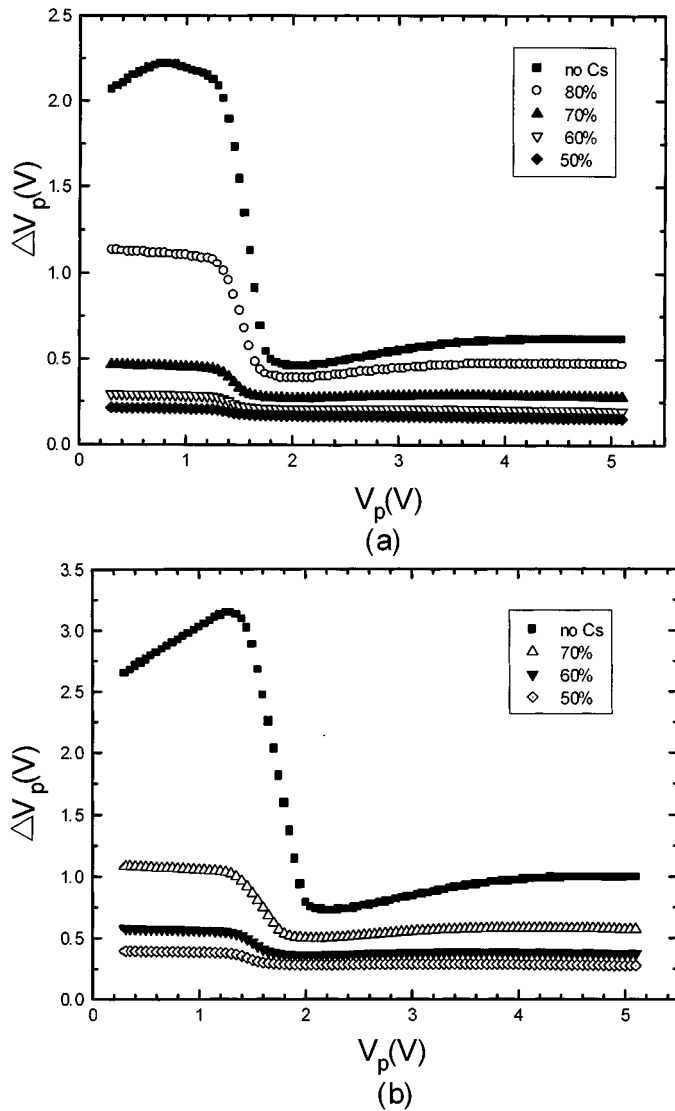


Fig. 3. Pixel voltage error as a function of data voltage for 10.4'' a-Si TFT LCD with various aperture ratio. (a) VGA, and (b) SVGA.

### B. E-O Characteristics for LC Pixel

E-O characteristics for LC pixel of 10.4'' VGA and SVGA a-Si TFT LCD with various aperture ratio is shown in Fig. 4. As a contrast, E-O characteristics for passive matrix LCD given in Section II is also provided. We found that there is a discrepancy in E-O characteristics between a-Si TFT LCD and the passive matrix LCD. In either full on-state or full off-state of LC pixel, the discrepancy is negligibly small, but it became evident when  $V_p$  is within the region between the threshold voltage and the saturation voltage.

Similar to  $\Delta V_p$ , for 10.4'' TFT LCD with the same resolution, the higher the aperture ratio is, the more significant the discrepancy is. On the other hand, the comparison of Fig. 4(a) and (b) shows the discrepancy for SVGA a-Si TFT LCD is more significant than that for VGA a-Si TFT LCD when the aperture ratio is the same. Here, we especially notice that, for SVGA without  $C_s$ -design, even though  $V_p$  is below the threshold voltage, the false signal appears due to the rotation of liquid crystal molecules caused by  $\Delta V_p$ .

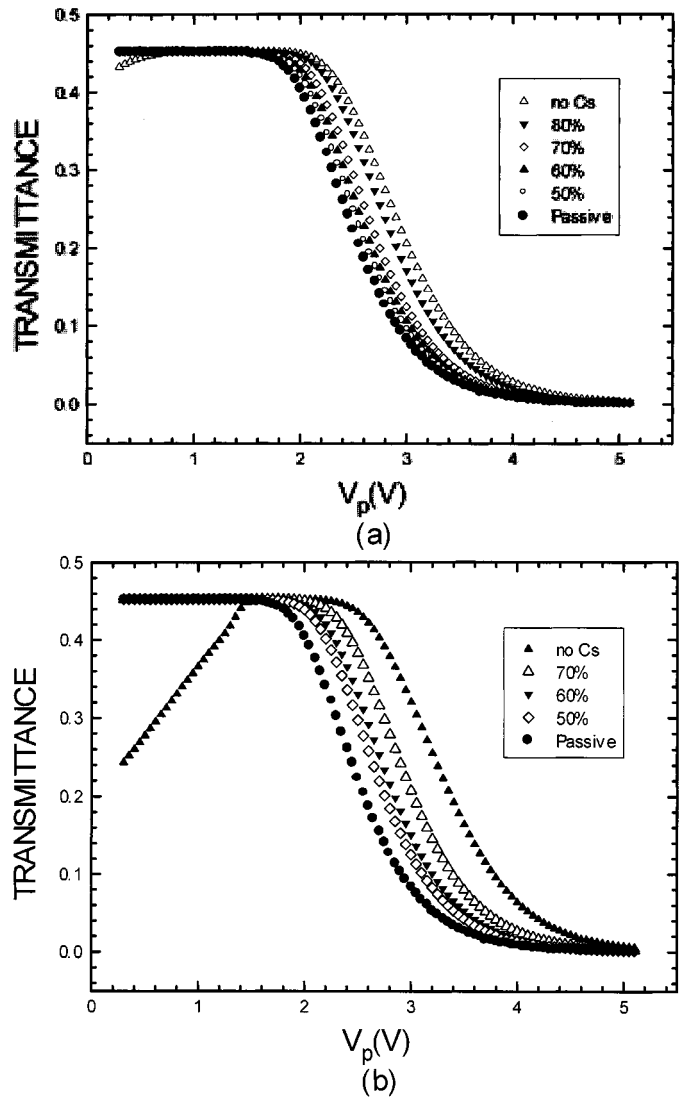


Fig. 4. E-O characteristics for 10.4'' a-Si TFT LCD with various aperture ratio. (a) VGA, and (b) SVGA.

As we know, the discrepancy in E-O characteristics is caused by the voltage error  $\Delta V_p$ , and this discrepancy will result in deterioration in gray scale. When the data voltage  $V_p$  is below the threshold voltage of LC pixel, though  $\Delta V_p$  is high, the discrepancy is not significant except SVGA a-Si TFT LCD without  $C_s$ -design. While  $V_p$  ranges from the threshold voltage to the saturation voltage,  $\Delta V_p$  decreases abruptly, and the discrepancy is significant. In the full on-state of LC pixel case,  $\Delta V_p$  is low, and a slight increase could be seen in  $\Delta V_p$ . The result suggests that the discrepancy in E-O characteristics is not proportional to  $\Delta V_p$ , and  $\Delta V_p$  will have evident impact on the E-O characteristics when the data voltage  $V_p$  ranges from the threshold voltage to the saturation voltage of LC pixel.

### V. CONCLUSION

In summary, the pixel electrode voltage error and E-O characteristics for 10.4'' VGA and SVGA a-Si TFT have been simulated regarding the change in LC dielectric constant. The results show that  $\Delta V_p$  changes with the data voltage  $V_p$  and that  $\Delta V_p$

affects E-O characteristics evidently when  $V_p$  is within the region between the threshold voltage and the saturation voltage.

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